



# Results of the laser-polished sample B-5.5 test (preliminary)

D. Tikhonov, Authors

**ARIES WP meeting** 

Presenter

Dmitry Tikhonov Early stage researcher

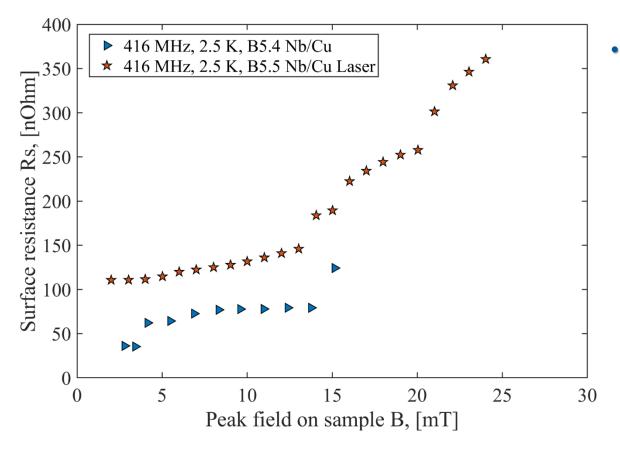
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# Results for pre-laser polishing and after for 2.5 K, ~400 MHz:

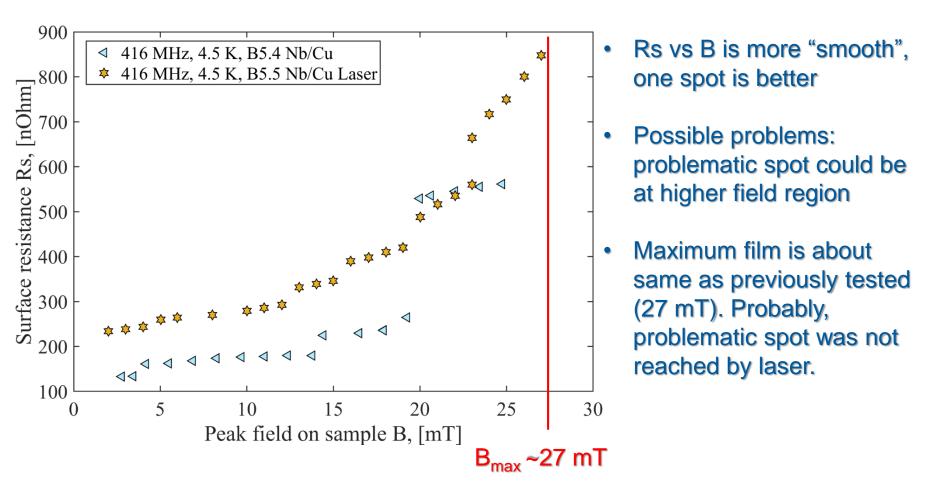


Higher surface resistance





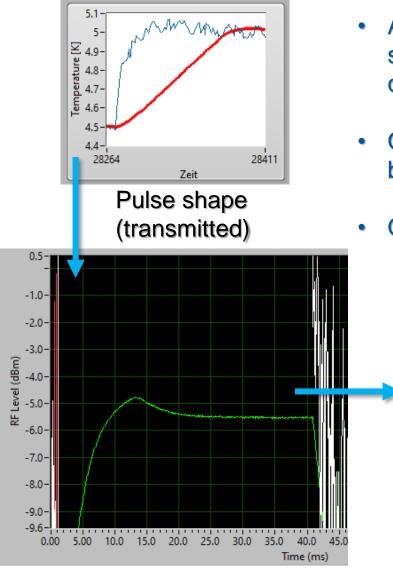
# Results for pre-laser polishing and after for 4.5 K, ~400 MHz:



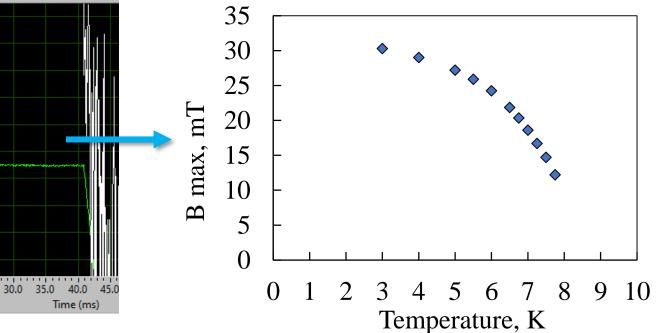


#### MAX FIELD, 416 MHZ





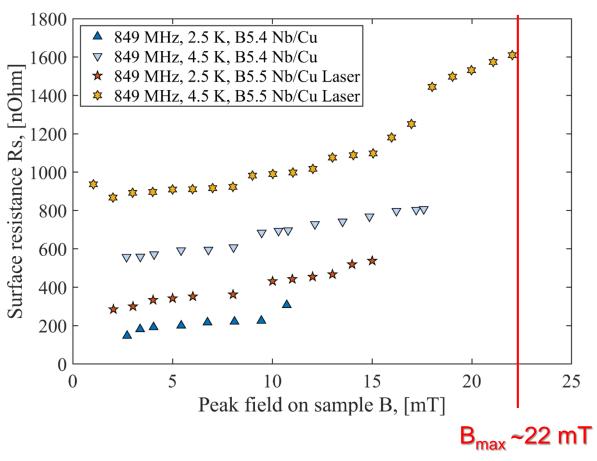
- At max field 27 mT, 416 MHz: Temperature significantly increased (but not complete quench)
- Only part of the film quenched (not full film because temperature stays <9.3K)</li>
- Quench field depends on temperature:







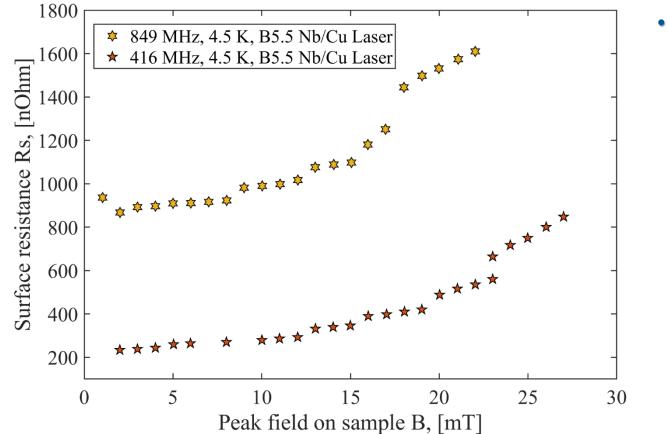
# Results for pre-laser polishing and after for ~850 MHz:



Maximum film is about 22 mT.







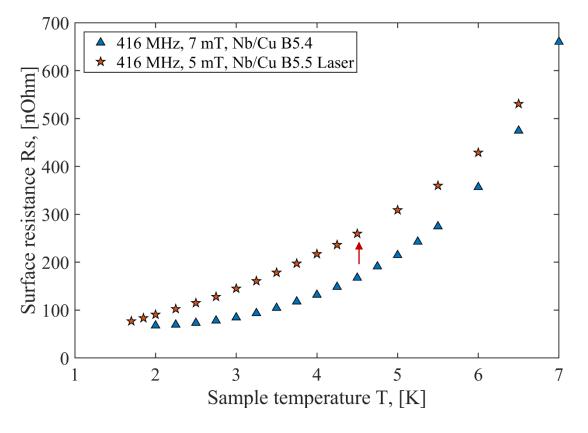








# Rs vs T results for pre-laser polishing and after for ~416 MHz:



- Rs vs T: Most of the 'additional' resistance come from temperature-depend part
- Residual resistance is approximately same:

Residual resistance 'eye' estimation (416 MHz):

	R <sub>res</sub>				
B-5.4	~67 nOhm				
B-5.5	~76 nOhm				

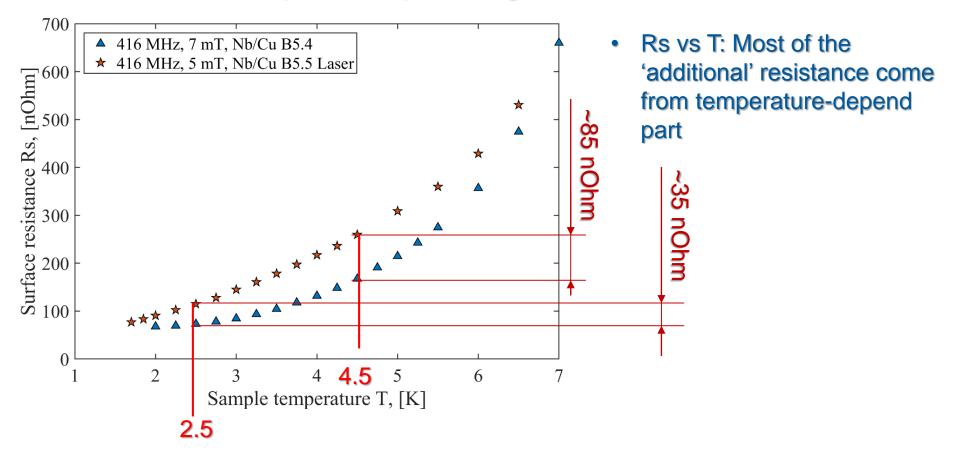






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# Rs vs T results for pre-laser polishing and after for ~416 MHz:

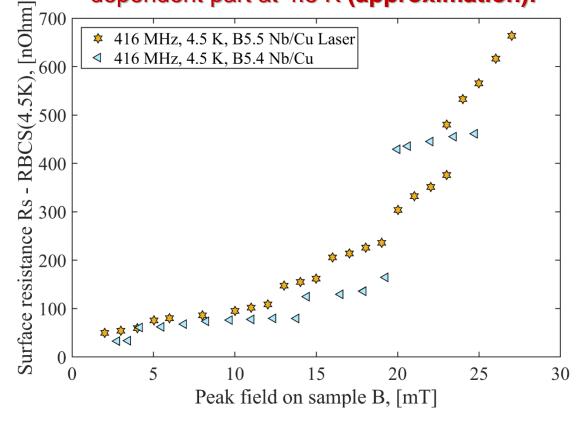






# Rs vs B results for pre-laser polishing and after for ~416 MHz:

# Rs with subtracted ~BCS temperature dependent part at 4.5 K (approximation):

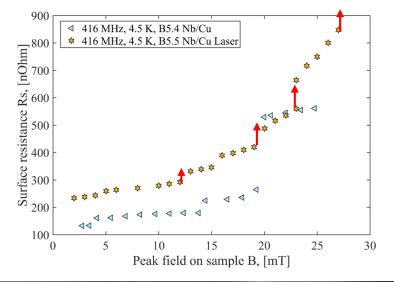


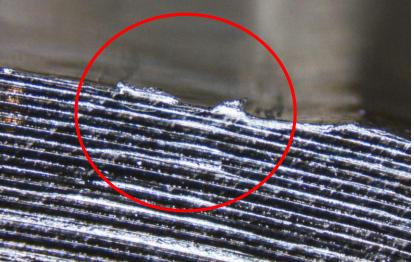
- Probably increased BCS came from impurities and defects due to wrong polishing procedure
- With subtracted BCS contribution from both tests the field dependent part is more or less comparable except higher field 'jump'

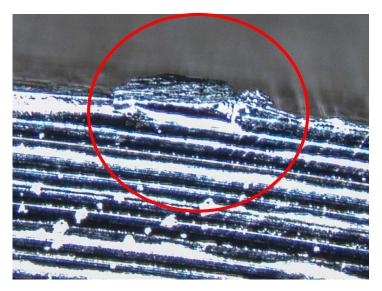
9

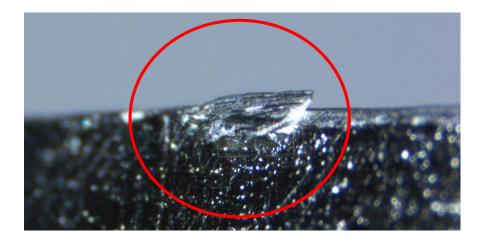








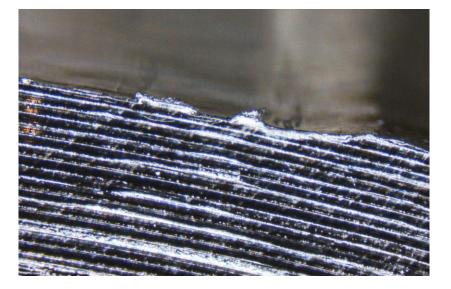












B-5 sample

#### **Conclusions:**

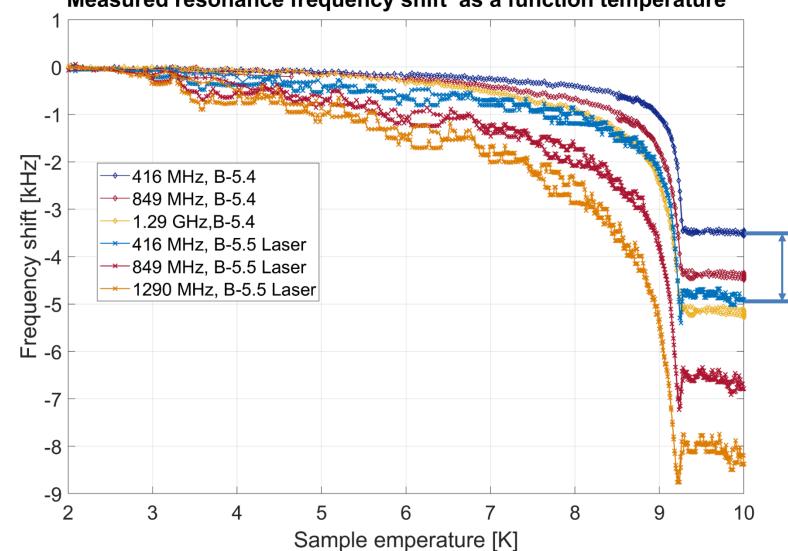
For the reliable data, next samples should be treated same way (flash etching, etc) to remove sharp pieces of Nb from edges



B-4 sample





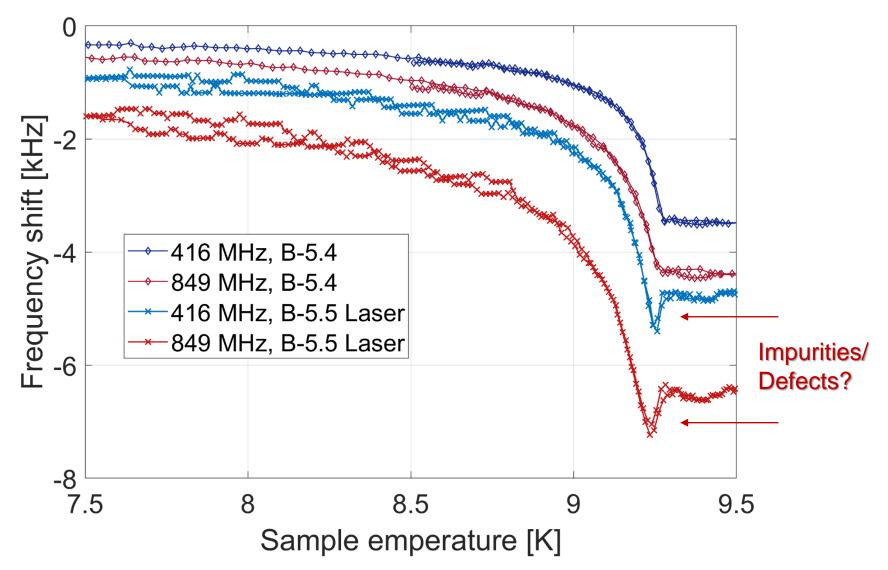






#### F VS T RESULTS FOR PRE-LASER POLISHING AND AFTER

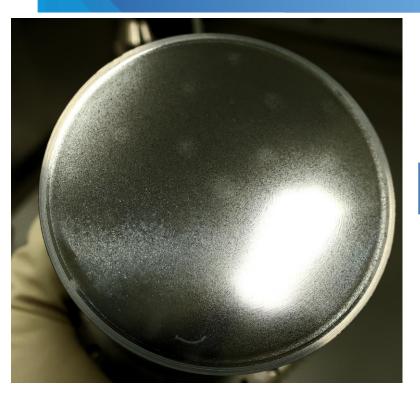


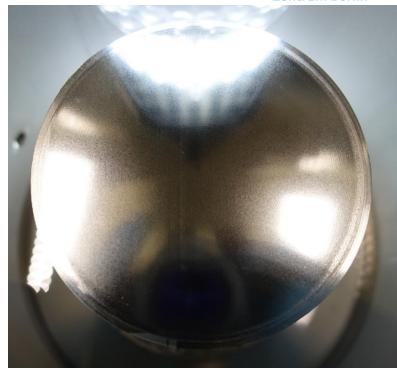




#### **POST-TEST SAMPLE SCAN: COMPARISON**







Pre LP:

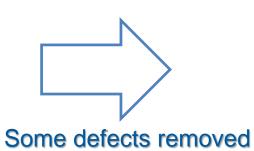
Post LP:



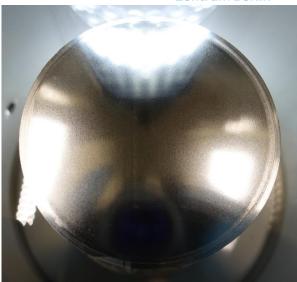
#### **POST-TEST SAMPLE SCAN: COMPARISON**







 Some defects removed or partially removed

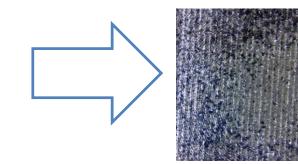


Post LP:



Pre LP:







POST-TEST SAMPLE SCAN: OVERVIEW





- Sample scanned with the laser microscope:
- Defects detection

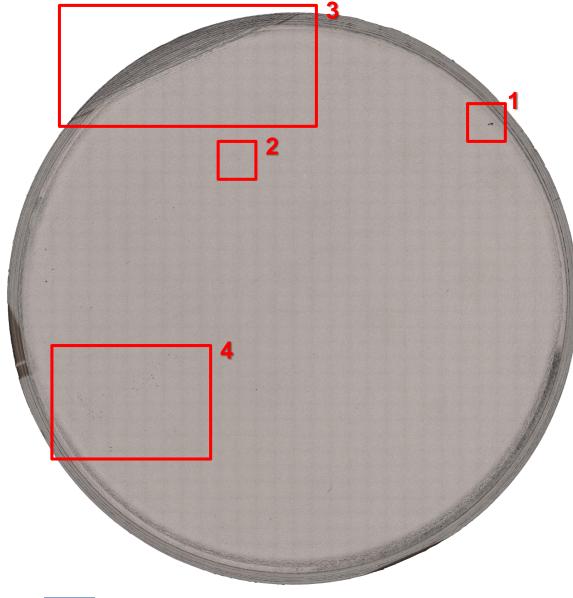
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- Roughness measurements
  - Full size JPEG picture (34 MB) and other data are on the CERNbox folder (<u>note,</u> <u>that some features = dust</u>)



#### **POST-TEST SAMPLE SCAN: SURFACE DEFECTS & ROUGHNESS**





# Some observed features:

- 1. Major defect near the edge
- 2. Minor craters in high field region
- 3. Laser traces (overpower?) near the edge
- 4. A "group of craters"





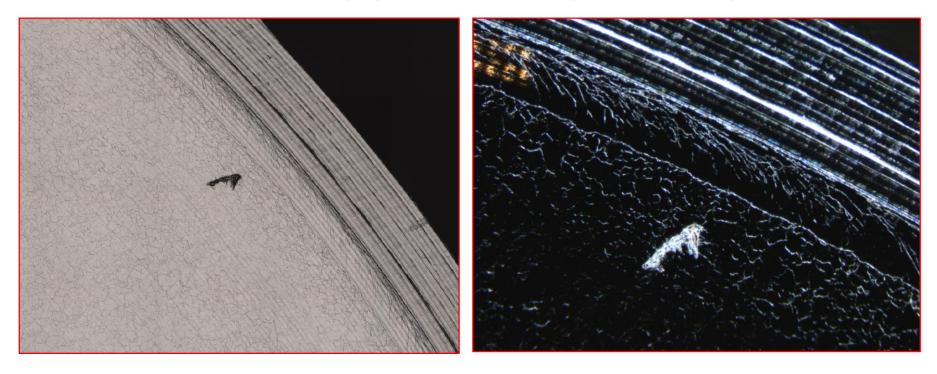




# Defect 1 found near the edge:

#### Laser microscope view (5x):

#### Optical microscope view:





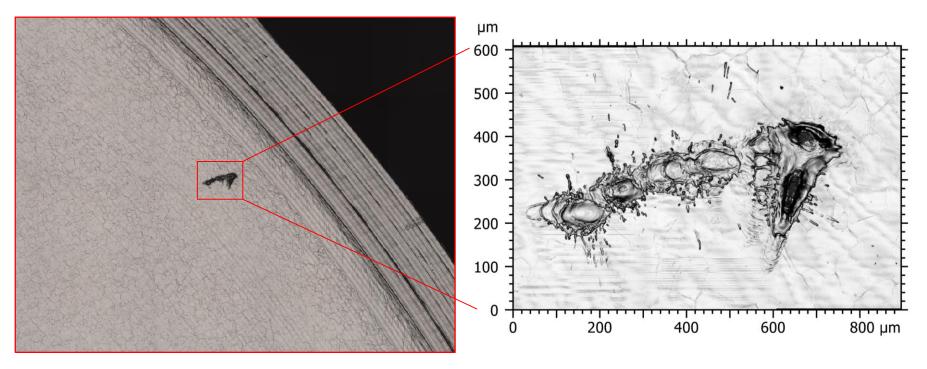




# Defect 1 found near the edge:

#### Laser microscope view (5x):

### Laser microscope view (20x):

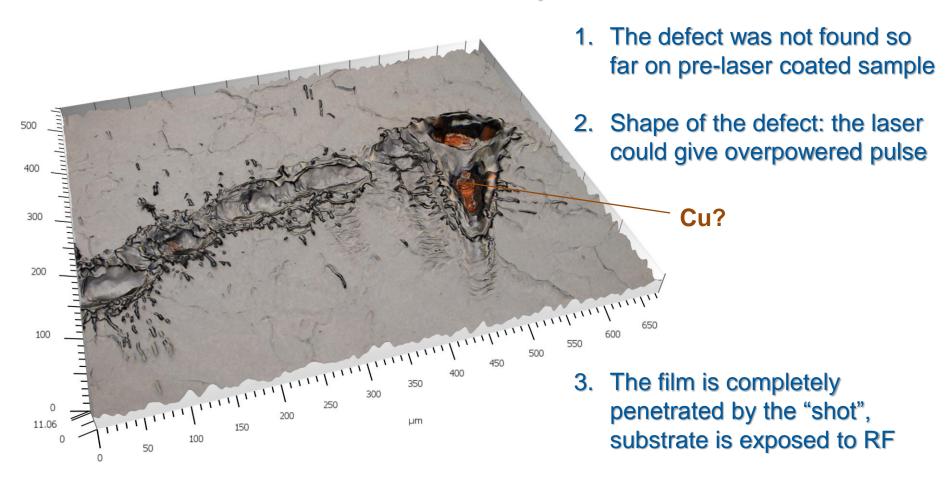








### Defect 1 view from optics in 3D:

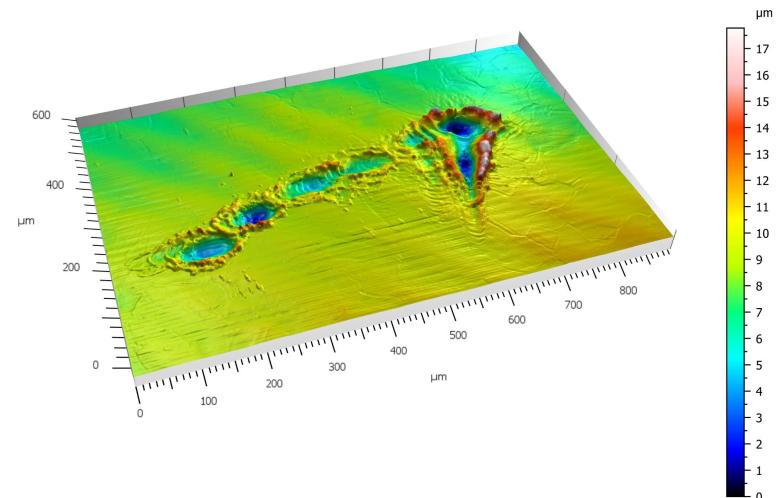








#### Defect 1 view in 3D:

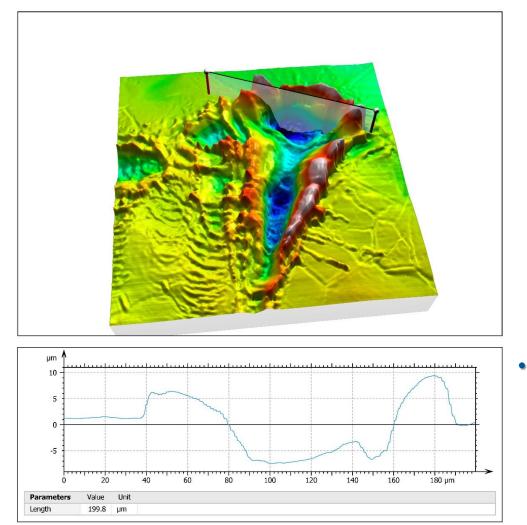








#### Defect 1 view in 3D:



The film deepness can be estimated about 5 mkm





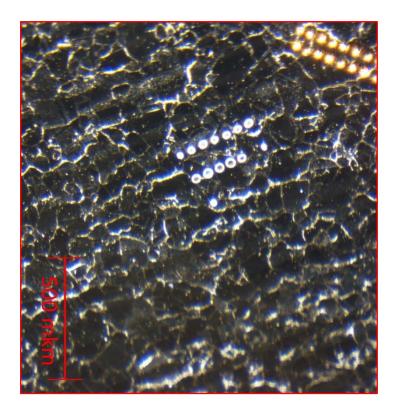


# Defect 2 found in the high RF field region:

#### Laser microscope view (5x):



#### Optical microscope view:





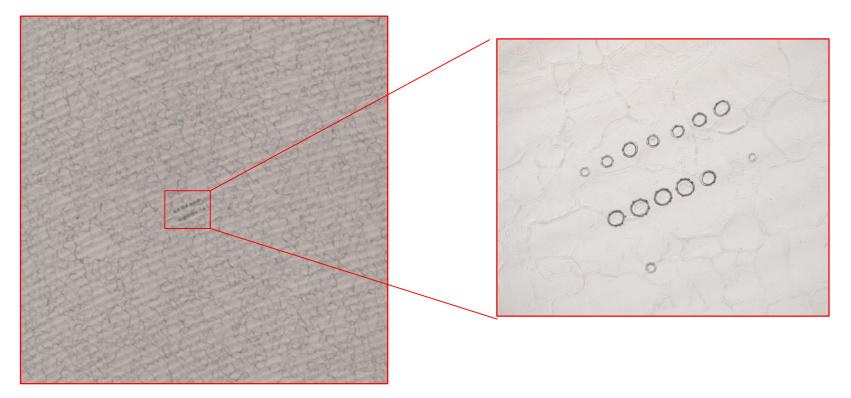




## Defect 2 found in the high RF field region:

#### Laser microscope view (5x):

#### Laser microscope view (20x):



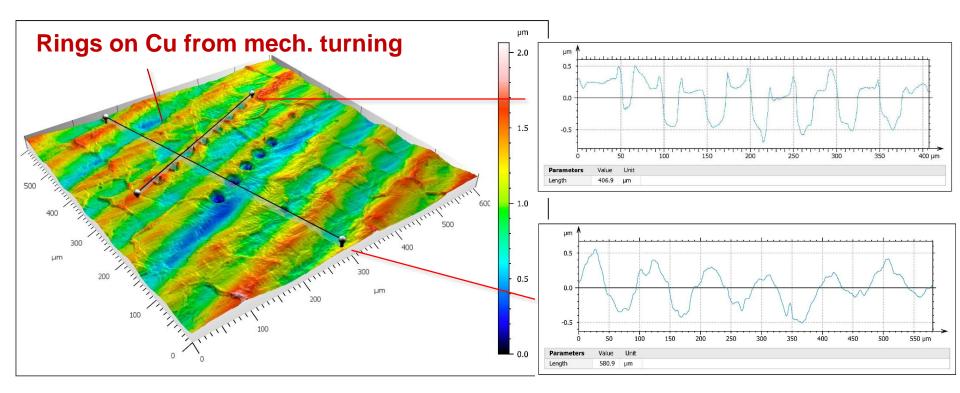






# Defect 2 found in the high RF field region:

- Defect again looks like a crater (series of craters), deepness up to 1 mkm
- Roughness from substrate shape (due to mechanical production) is about 1 mkm

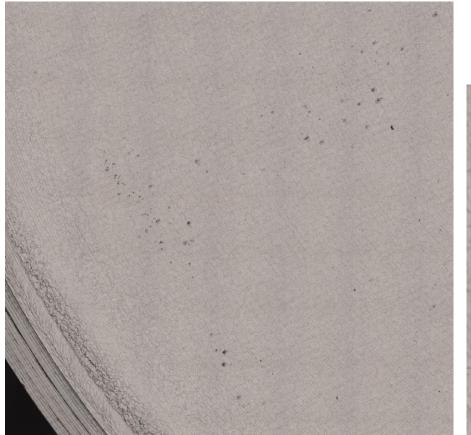








### Laser microscope view (5x):





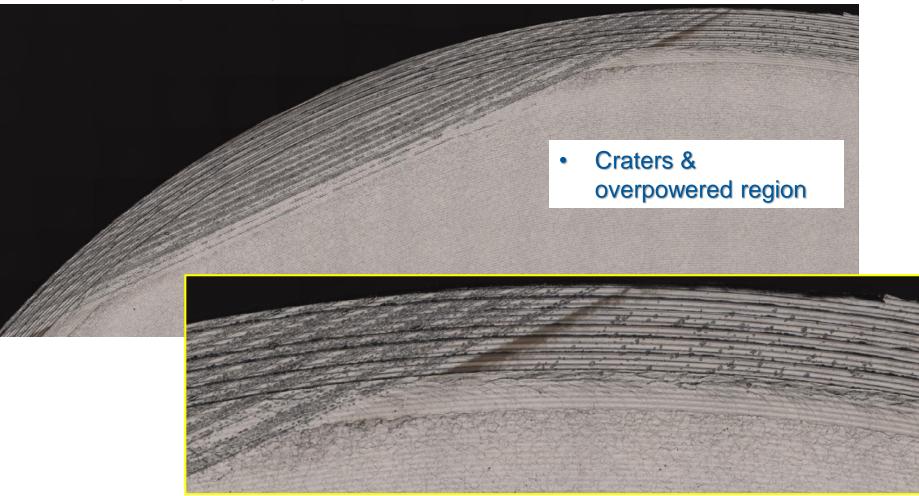








#### Laser microscope view (5x):





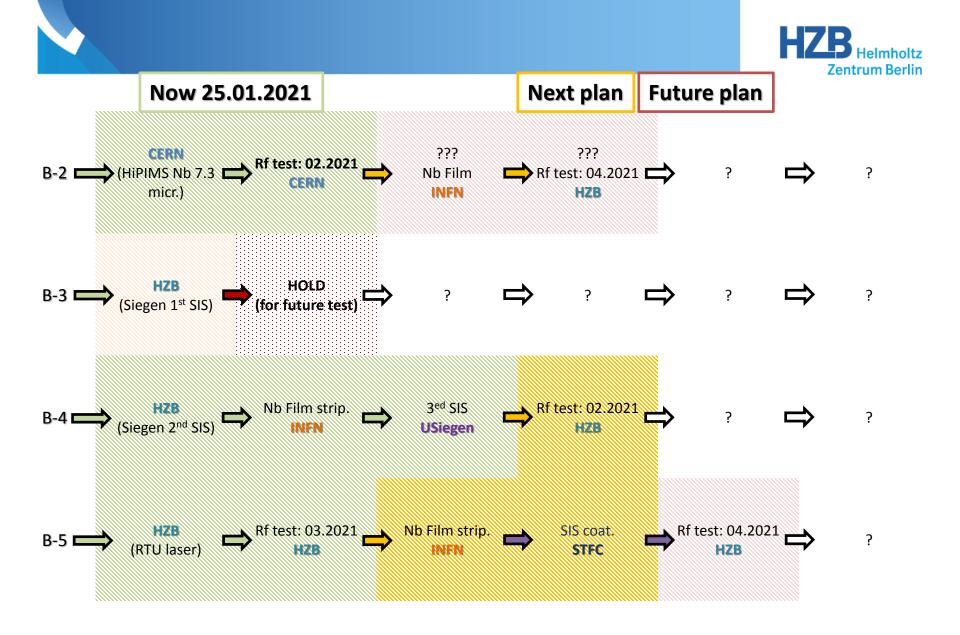




# CONCLUSIONS

- Laser polishing practically can work
- Minor improvements at Rs vs B behavior. The problem with the rough edges is still present, and % of contribution of it to the final result is not clear.
- Film (probably) got some contaminations and defects during the process (conclusion from R<sub>BCS</sub> and FvsT data).
- The process needs to be adjusted and surface analyzed more carefully.









	Actual Hrs	Progress	FEBR	UARY 2021	MARCH 2021		APRI		MAY 2021	
<ul> <li>HZB other sample tests</li> </ul>	0 hrs	0%		<b>12 15 16 17 18 19 22 23 24 25 26</b> F M T W T F M T W T F	5 1 2 3 4 5 8 9 10 11 12 15 16 17 M T W T E M T W T E M T W	18 19 22 23 24 25 26 29 30 31 T F M T W T F M T W		<b>16 19 20 21 22 23 26 27 28 29 30</b> F M T W T F M T W T F		13 14 17 18 19 2 T F M T W
•								F W I W I F WI I W I F	UNITE WE FOR THE	1 12 101 1 102
CEA baseline	0					CEA basel				
▼ B-1 sample	0 hrs	0%								
<ul> <li>B-2 sample</li> </ul>	0 hrs	21%								
CERN RF test	0	100%	CERN RF test							
HZB RF test B-2 (c	0						HZB RF te			
INFN strip.	0							INFN strip.		
INFN coat NB	0							INFN coat N	В	
HZB RF test B-2 IN	0									HZB RF test B
▼ B-4 sample	0 hrs	50%								
INFN strip.	0	100%	INFN strip.							
USiegen coat SIS	0	100%		USiegen c						
HZB RF test B-4 SIS	0				HZB RF test B-4 SIS					
<ul> <li>B-5 sample</li> </ul>	0 hrs	17%	-							
HZB RF test B-5 R	0	100%	HZB RF test B-5							
INFN strip.	0				INFN strip.					
STFC coat SIS	0					STFC o	coat			
HZB RF test B-5 ST	0							HZB RF test B-5 STFC		





# SUGGESTED NEXT STEPS

- If possible (not at HZB): Any analyses regarding molecular components of the film and/or SEM microscope scan
- Suggestions: Stripping of the top layer of the film and retesting to see if the contaminations are removed?

